

02975.000130

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kazuo IIZUKA et al.

Application No.: 10/762,468

Filed: January 23, 2004

For: PROJECTION EXPOSURE MASK, PROJECTION
EXPOSURE APPARATUS, AND PROJECTION
EXPOSURE METHOD



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: Examiner: P. B. Kim
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: Group Art Unit: 2851
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: Confirmation No.: 5472
)
:
) November 22, 2005
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)

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

LETTER TRANSMITTING REPLACEMENT DRAWING SHEET


Sir:

Transmitted herewith is one (1) formal drawing sheet, corrected Figures 3A-3E, to be substituted for the corresponding drawing sheet currently on file in the above-identified application. The labels on this figure have been changed in accordance with preferred practice.

Favorable consideration is requested.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,


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